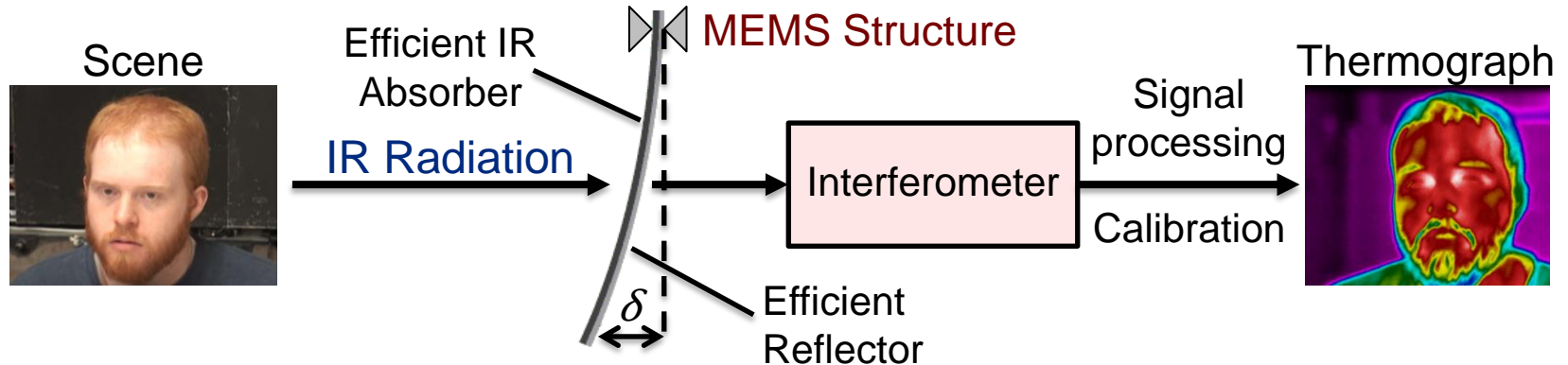
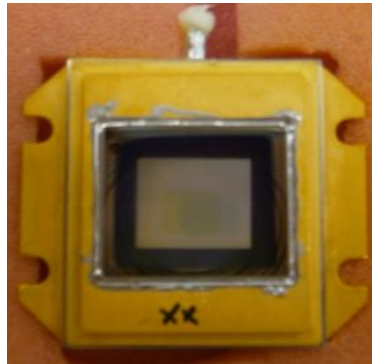
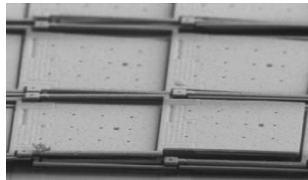


Realization, characterization, and application of an uncooled MEMS sensor for real-time infrared imaging

C. Furlong, F. Pantuso, I. Dobrev, M. Khaleghi, and E. Tripp



MEMS Structures

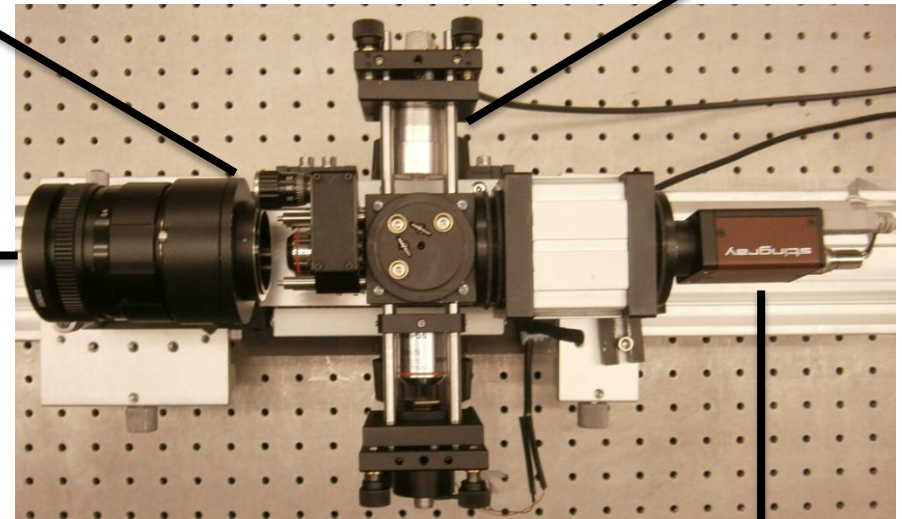


MEMS Sensor

LWIR Lens

Linnik Interferometer

620nm LED



Camera

- MEMS structures: 20-50 μ m length
- Layer Thickness: 1 μ m
- Response: on the order of nm/ $^{\circ}$ K
- IR Absorber: Silicon Nitride
- Reflector: Aluminum or Gold

